



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

24/Amend B
8.12.03
C. Moore

Inventors: James M. Holden; William A. McGahan; Richard A. Yarussi; Pablo I. Rovira; Roger R. Lowe-Webb
Assignee: Nanometrics Incorporated
Title: Apparatus And Method For The Measurement Of Diffracting Structures
Serial No.: 09/670,000 Filing Date: September 25, 2000
Examiner: Chih-Cheng Glen Kao Group Art Unit: 2882
Docket No.: NAN022 US Confirmation No. 3656

COMMISSIONER FOR PATENTS
Washington, D. C. 20231

RESPONSE TO OFFICE ACTION

Dear Sir:

This Response to Office Action is responsive to the September 13, 2002, Office Action, which has a statutorily shortened period for response that ends December 13, 2002. A Petition for Extension of Time under 37 CFR 1.136(a) is attached hereto, giving Applicants until January 13, 2003 to respond. Please enter the following amendments before taking action on the merits of the above-referenced application.

In the Specification

Please replace the paragraph at page 1, line 23 to line 27 with the following paragraph:

One tool that is sometimes used to measure diffracting structures is a scatterometer. Scatterometry is an angle-resolved measurement and characterization of light scattered from a structure. Scatterometry is discussed in detail in U.S. Serial No. 09/036,557, filed March 6, 1998, now US 6,483,580 B1, which is assigned to KLA-Tencor Corporation, which has an International Publication No. WO 99/45340, dated September 10, 1999, and which is incorporated herein by reference.

Santa Clara, California
January 10, 2003

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